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OFGS File No: P/1250-258

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of
MIYA, Katsuhiko et al

New York, New York
Date: March 1, 2005

Serial No.: 10/648,918

Group Art Unit:

Date Filed: August 27, 2003

For: SUBSTRATE PROCESSING APPARATUS AND SUBSTRATE PROCESSING
METHOD DRYING SUBSTRATE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

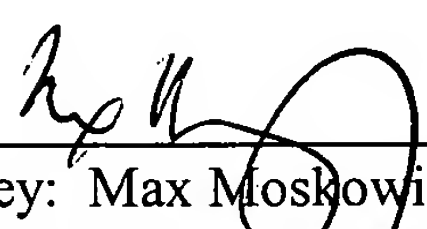
STATUS INQUIRY LETTER

Sir:

We filed the above application with the U. S. Patent and Trademark Office on August 27, 2003.

As of this date, we have not received a first Office Action from the Patent Office. Kindly advise us of the status of this application.

Respectfully Submitted,



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